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FEB 03 2006cket No.: 21776-00052-US1
(PATENT)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Nobuhiro Miki et al.

Confirmation No.: 6222

Application No.: 10/614,244

Filed: July 8, 2003

Art Unit: 1734

For: RESIST FILM REMOVAL APPARATUS AND
RESIST FILM REMOVAL METHOD

Examiner: Osele, Mark A.

AMENDMENT IN RESPONSE TO NON-FINAL OFFICE ACTION

MS Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

February 3, 2006

Dear Sir:

INTRODUCTORY COMMENTS

In response to the Office Action dated October 5, 2005, the period of response having been extended by one (1) month until February 5, 2006, please amend the above-identified U.S. patent application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 5 of this paper.

Deposit account authorization for extension of time fees has been separately provided.